



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Clark T.-C. Nguyen, et al.

Group Art Unit:

Serial No.: 10/737,363

Examiner:

Filed: December 16, 2003

For: MICROMECHANICAL RESONATOR DEVICE AND
METHOD OF MAKING A MICROMECHANICAL DEVICE

Attorney Docket No.: UOM 0285 PUSP

INFORMATION DISCLOSURE STATEMENT

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In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and § 1.97-1.98, the references listed and identified on the attached Forms PTO/SB08A and/or SB08B are being submitted herewith for consideration by the Examiner.

While this Statement is being filed in compliance with the duty of disclosure, citation of the attached references is not to be construed as an admission that any of the reference(s) are "material" as defined under 37 C.F.R. § 1.56(b).

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If the filing date of this application is on or before June 30, 2003, a copy of each reference listed on the attached Forms PTO/SB08A and/or SB08B is included herewith. If this application was filed after June 30, 2003, copies of any cited U.S. patent/application references have not been included. Consideration and entry into the record of these references is respectfully requested.

Respectfully submitted,

Clark T.-C. Nguyen, et al.

By: 

David R. Syrowik

Reg. No. 27,956

Attorney/Agent for Applicant

Date: March 24, 2004

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PTO/SB/08A (10-96) [MODIFIED]

Approved for use through 10/31/99. OMB 0651-0031

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 <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p>(use as many sheets as necessary)</p>				Complete if Known	
				Application Number	10/737,363
				Filing Date	December 16, 2003
				First Named Inventor	Clark T.-C. Nugyen, et al.
				Group Art Unit	
				Examiner Name	
Sheet	1	of	3	Attorney Docket Number	UOM 0285 PUSP

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.

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Substitute for Form 1449B/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet

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of

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Examiner Name	

Attorney Docket Number UOM 0285 PUSP

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		NGUYEN, CLARK, T.-C., Microelectromechanical Components For Miniaturized Low-Power Communications, Proceedings, 1999 IEEE MTT-S International Microwave Symposium RF MEMS Workshop, Anaheim, California, June 18, 1999, pp. 48-77	
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		HSU, WAN-THAI, ET AL., A Sub-Micron Capacitive-Gap Process For Multiple-Metal-Electrode Lateral Micromechanical Resonators, Technical Digest, IEEE Int. Micromechanical Systems Conf., Interlaken, Switzerland, January 21-25, 2001, pp. 349-352	
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